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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Filing Date ..... July 22, 1999  
Inventor ..... Sujit Sharan et al.  
Assignee ..... Micron Technology, Inc.  
Group Art Unit ..... 1746  
Examiner ..... Shamim Ahmed  
Attorney's Docket No. .... MI22-1106  
Title: Plasma Etching Process

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

References -- See Attached Form PTO-1449

The attached Form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Copies of the cited art are included herewith. No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 3-12-02

By:   
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